

OK; Omega Air, Inc., Alexandria, VA (Controlling Entity: Omega Air, Dublin Airport, Ireland); Space Access, LLC, Palmdale, CA; Spectrum Astro, Inc., Gilbert AZ; Stellex Aerostructures, Inc., Woodland Hills, CA (Controlling Entity: Stellex Technologies, Inc., Woodland Hills, CA); Swales Aerospace, LLC, Beltsville, MD; Vought Aircraft Industries, Inc., Dallas, TX (Controlling Entity: The Carlyle Group, Washington, DC); W.L. Gore & Associates, Inc., Newark, DE; BAE Systems North America, Inc., Rockville, MD; GenCorp, Sacramento, CA; Smiths Group PLC, London, England, UK, for the activities of Smiths Aerospace Actuation Systems, Los Angeles, Duarte, CA; Triumph Group, Inc.; Wayne, PA; Analytical Graphics, Inc., Malvern, PA; Atlantic Research Corporation, Gainesville, VA (Controlling Entity: Sequa Corporation, New York, NY); Aviall, Inc., Dallas TX; Ball Aerospace & Technologies Corporation, Boulder, CO; Cubic Corporation, San Diego, CA; Curtiss-Wright Corporation, Lyndhurst, NJ; Dassault Falcon Jet Corporation, South Hackensack, NJ (Controlling Entity: Dassault Aviation, France); Davis Tool, Inc., Hillsboro, OR; DRS Technologies, Inc., Parsippany, NJ; Embraer Aircraft Corporation, Brazil; Exostar, LLC, Herndon, VA; Fairchild Dornier Corporation, Wessling, Germany; The Fairchild Corporation for the activities of Fairchild Fasteners, Dulles, VA; General Atomics Aeronautical Systems, Inc., San Diego, CA (Controlling Entity: General Atomics, San Diego, CA); Genuity Solutions, Inc., Woburn, MA; GKN Aerospace, Inc., Reston, VA (Controlling Entity: GKN Westland Aerospace division of GKN, PLC, Worcestershire, UK); ITT Industries, Inc., McLean, VA.

2. Delete the following companies as "Members" of the Certificate within the meaning of section 325.2(1) of the Regulations (15 CFR 325.2(1)): Aerojet-General Corporation, Sacramento, CA; Allied Signal Inc., Morristown, NJ; Hughes Electronic Corporation, El Segundo, CA; CMS, Inc., Tampa, FL; Coltech Industries, Inc., New York, NY; Digital Equipment Corporation, Maynard, MA; Cordant Technologies, Inc., Ogden, UT; Dowty Decoto, Inc., Duarte, CA; Dynamic Engineering Incorporated, Newport News, VA; Gulfstream Aerospace Corporation, Savannah, GA; Interturbine Corporation, Peabody, MA; ITT Defense and Electronics Inc., McLean, VA; Litton Industries, Inc., Woodland Hills, CA; Lucas Industries, Inc., Reston, VA; Marconi North America Inc., Wayne, NJ; Pacific Scientific Company, Duarte, CA;

Sundstrand Corporation, Rockford, IL; Triumph Controls, Inc., North Wales, PA; Veridian Corporation, Alexandria, VA.

3. Change the listings of the current Members as follows: "BF Goodrich; Akron, OH" to "Goodrich Corporation, Charlotte, NC"; "HEICO Corporation, Hollywood, FL" to "HEICO Corporation; Miami, FL"; "B.H. Aircraft Company, Incorporated, Farmingdale, NY" to "B.H. Aircraft Company, Incorporated, Rokonkoma, NY."

Dated: December 5, 2001.

Vanessa M. Bachman,

Acting Director, Office of Export Trading Company Affairs.

[FR Doc. 01-30666 Filed 12-11-01; 8:45 am]

BILLING CODE 3510-DR-P

DEPARTMENT OF COMMERCE

International Trade Administration

Overseas Trade Missions

AGENCY: International Trade Administration, Department of Commerce.

ACTION: Revised notice.

SUMMARY: This corrects dates shown for two Department of Commerce overseas trade missions listed in **Federal Register**, Vol. 66, No. 233, Tuesday, December 4, 2001, page 63019. The notice for these two trade missions should read:

The Department of Commerce invites U.S. companies to participate in the below listed overseas trade missions. For a more complete description of each trade mission, obtain a copy of the mission statement from the Project Officer indicated for each mission below. Recruitment and selection of private sector participants for these missions will be conducted according to the Statement of Policy Governing Department of Commerce Overseas Trade Missions dated March 3, 1997.

Benelux Environmental Technologies Trade Mission

The Hague, Netherlands, and Brussels Belgium, March 4-8, 2002, Recruitment closes on January 18, 2002.

FOR FURTHER INFORMATION CONTACT: Mr. David Fiscus, U.S. Department of Commerce, telephone 202-482-1599, or e-mail David.Fiscus@mail.doc.gov.

Benelux Information and Communications Technology Trade Mission

Amsterdam, Netherlands, and Brussels Belgium, May 13-17,

2002, Recruitment closes on April 10, 2002.

FOR FURTHER INFORMATION CONTACT: Mr. David Fiscus, U.S. Department of Commerce, telephone 202-482-1599, or e-mail David.Fiscus@mail.doc.gov.

FOR FURTHER INFORMATION CONTACT: Thomas Nisbet, U.S. Department of Commerce, telephone 202-482-5657, or e-mail Tom_Nisbet@ita.doc.gov.

Dated: December 7, 2001.

Thomas H. Nisbet,

Director, Promotion Planning and Support Division, Office of Export Assistance and Business Outreach.

[FR Doc. 01-30758 Filed 12-11-01; 8:45 am]

BILLING CODE 3510-D-R-F-P

DEPARTMENT OF COMMERCE

National Institute of Standards and Technology

Government-Owned Inventions Available for Licensing

AGENCY: National Institute of Standards and Technology, Commerce.

ACTION: Notice of Government owned inventions available for licensing.

SUMMARY: The inventions listed below are owned in whole or in part by the U.S. Government, as represented by the Department of Commerce, and are available for licensing in accordance with 35 U.S.C. 207 and 37 CFR part 404 to achieve expeditious commercialization of results of federally funded research and development.

FOR FURTHER INFORMATION CONTACT: Technical and licensing information on these inventions may be obtained by writing to: National Institute of Standards and Technology, Office of Technology Partnerships, Building 820, Room 213, Gaithersburg MD 20899; Fax 301-869-2751. Any request for information should include the NIST Docket No. and Title for the relevant invention as indicated below.

SUPPLEMENTARY INFORMATION: NIST may enter into a Cooperative Research and Development Agreement ("CRADA") with the licensee to perform further research on the inventions for purposes of commercialization. The inventions available for licensing are:

[NIST Docket Number: 96-006D]

Title: Method and Composition for Promoting Improved Adhesion to Substrates.

Abstract: The invention is jointly owned by the U.S. Government, as represented by the Secretary of Commerce, and the American Dental Association Health Foundation. The

Department of Commerce's ownership interest in this invention is available for licensing. An etchant primer composition is provided which includes (a) a compound having the formula $RN(CH_2YCO_2M)_2$ wherein $R=R^1$ or R^2 ; R^1 =an aromatic group; R^2 =a conjugated aliphatic group; Y =a single bond, CH_2 , $CHCH_3$ or $C=CH_2$; and each M is independently H, an alkali metal, an alkaline earth metal, aluminum, a transition or redox metal or an alkyl group having 1 to 18 carbon atoms, with the proviso that when both M groups are alkyl groups, the compound corresponding to formula I be capable of being easily hydrolyzed, displaced or exchanged with other reagents present in the etchant/primer composition and (b) a polar solvent system. An etchant/primer/adhesive monomer composition is also provided which includes the etchant/primer composition and an adhesive monomer system. One and two step simplified methods for adhering and for preparing substrate surface, such as a dental substrate surface, to a polymeric material are also provided. Kits which may be used with these compositions and methods are also provided.

[NIST Docket Number: 97-036US]

Title: Silicon-on-Insulator Substrates Using Low Dose Implantation

Abstract: The invention is jointly owned by the U.S. Government, as represented by the Secretary of Commerce, and IBM Corp. The Department of Commerce's ownership interest in this invention is available for licensing. An SOI Substrate and method of forming is described incorporating the steps of implanting oxygen under two conditions and performing two high temperature anneals at temperatures above 1250.degree C. and above 1300.degree C, respectively, at two respective oxygen concentrations. The invention overcomes the problem of high SOI substrate fabrication cost due to ion implant time and of getting high quality buried oxide (BOX) layers below a thin layer of single crystal silicon.

[NIST Docket Number: 00-016US]

Title: Method and Apparatus for Entrainment Mixing of Vapor Into Liquids.

Abstract: Mixing of fluids is a central component to innumerable operations in chemical processing on the plant floor and also in many laboratory operations. Most mixing applications simply require the efficient blending of fluids present in a single phase, such as the mixing of the individual components of a liquid. For these applications, magnetic stirrers often provide a convenient and efficient

bending without creating ambient air entrainment into the liquid. This is especially true of fluid mixing operations done in the laboratory. There are many other applications, however, in which the entrainment of a vapor phase with a liquid is specifically desired. Examples of these applications include mixing in two-phase reaction vessels and apparatus to measure vapor liquid equilibrium. These mixing operations are difficult to accommodate with magnetic stirrers because the vast majority of such stirrers are designed not to entrain vapor. In this disclosure, we teach a novel design of a mixing rotor that efficiently mixes the liquid phase and also achieves entrainment of vapor into the liquid.

[NIST Docket Number: 00-031US]

Title: Polyelectrolyte Derivatization of Microfluidic Devices.

Abstract: The invention describes the use of polyelectrolyte multilayers (PEMs) to alter the surface of microchannel surfaces was obtained by coating the channels with alternating layers of poly (allyamine hydrochloride) and poly (styrene sulfonate). The PEMs are easily fabricated and provide a means for controlling the flow direction and the electrosmotic mobility in the microchannels.

[NIST Docket Number: 01-008US]

Title: Chemical Modification of Substrates by Photo-ablation Under Different Local Atmospheres and Chemical Environments for the Fabrication of Microstructures.

Abstract: The invention consists of a one step photo-ablation process that can simultaneously use different gas or liquid atmospheres to pattern microchannels and functionalize the surface of polymer substrates.

Dated: December 4, 2001.

Karen H. Brown,
Deputy Director.

[FR Doc. 01-30629 Filed 12-11-01; 8:45 am]

BILLING CODE 3510-13-M

DEPARTMENT OF COMMERCE

National Institute of Standards and Technology

Announcing a Meeting of the National Conference on Weights and Measures

AGENCY: National Institute of Standards and Technology, Commerce.

ACTION: Notice of meeting.

SUMMARY: Notice is hereby given that the 87th Interim Meeting of the National Conference on Weights and Measures will be held January 27 through January

30, 2002, at the Hyatt Regency Bethesda, Bethesda, MD. The meeting is open to the public. The National Conference on Weights and Measures is an organization of weights and measures enforcement officials of the States, counties, and cities of the United States and private sector representatives. The Interim Meeting of the Conference as well as the Annual Meeting to be held next July (a notice will be published in the **Federal Register** prior to such meeting), brings together enforcement officials, other government officials, and representatives of business, industry, trade associations, and consumer organizations to discuss subjects that relate to the field of weights and measures technology and administration. Pursuant to (15 U.S.C. 272B), the National Institute of Standards and Technology supports the National Conference on Weights and Measures in order to promote uniformity among the States in the complex laws, regulations, test methods, and testing equipment that comprise regulatory control by the States of commercial transactions involving weighing and measurement.

DATES: The meeting will be held January 27-January 30, 2002.

LOCATION OF MEETING: Hyatt Regency Bethesda, Bethesda, MD.

FOR FURTHER INFORMATION CONTACT: Henry V. Oppermann, Director of NIST Office of Weights and Measures, 100 Bureau Drive, Stop 2600, Gaithersburg, MD 20899-2600. Telephone (301) 975-4004, or E-mail owm@nist.gov.

Dated: December 4, 2001.

Karen H. Brown,
Acting Director.

[FR Doc. 01-30628 Filed 12-11-01; 8:45 am]

BILLING CODE 3510-13-M

COMMITTEE FOR THE IMPLEMENTATION OF TEXTILE AGREEMENTS

Withdrawal of Short Supply Petition under the North American Free Trade Agreement (NAFTA)

December 6, 2001.

AGENCY: Committee for the Implementation of Textile Agreements (CITA).

ACTION: Withdrawal of petition concerning a modification of the NAFTA rules of origin for gimped yarn made from certain filament yarn of nylon.

SUMMARY: On September 5, 2001 the Chairman of CITA received a petition from Unifi, Inc. (Unifi) alleging that